



## Liquid Chemical Japan TC Chapter Meeting Summary and Minutes (Draft)

Japan Standards Spring 2019 Meetings  
April 15, 2019, Begin [15:00] – End [17:00]  
SEMI Japan, Tokyo, Japan

### TC Chapter Announcements

*Next TC Chapter Meeting*

Dec 11-13, 2019 (TBD)

SEMICON Japan, Tokyo Big Sight, Tokyo, Japan.

### Table 1 Meeting Attendees

*Italics indicate virtual participants*

**Co-Chairs:** Hiroshi Tomita (Toshiba Memory), Hiroyuki Araki (SCREEN Semiconductor Solutions)

**SEMI Staff:** Mizue Iwamura

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
ADVANCE ELECTRIC	Sasao	Kimihito	SCREEN Semiconductor Solutions	Araki	Hiroyuki
Nihon Entegris	Nagafuchi	Takuya	SCREEN Semiconductor Solutions	Sato	Masanobu
Organo	Futatsuki	Takashi	Shin-Etsu Polymer	Odajima	Satoshi
Organo	Sugawara	Hiroshi	Tohoku Technologies	Kunimoto	Fumitomo
Pall	Mizuno	Takehito	Tokyo Electron	Saito	Misako
Pall	Tomoyuki	Takakura	Toshiba Memory	Tomita	Hiroshi
Pall	Tsuzuki	Shuichi	Toshiba Nano Analysis	Murata	Toshiharu
PMS Division / Spectris Co., Ltd.	Kato	Kazutoshi			
Rion	Kondo	Kaoru	SEMI Japan	Iwamura	Mizue

### Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
Trace Metal Analysis for High Pure IPA Task Force	-	Takuya Nagafuchi (Nihon Entegris) Hiroshi Sugawara (Organo)
Liquid Filter Task Force	Takuya Nagafuchi (Nihon Entegris) Takehito Mizuno (Pall)	Takuya Nagafuchi (Nihon Entegris) Tomoyuki Takakura (Pall)

### Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
-	Trace Metal Analysis for High Pure IPA Task Force

**Table 4 Ballot Results**

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6491	Reapproval of SEMI C82-0713: Test Method for Particle Removal Performance of Liquid Filter Rated 20 to 50 nm With Liquid-Borne Particle Counter	<b>Passed</b> , as balloted

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

**Table 5 Activities Approved by the GCS between meetings of the TC Chapter**

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
6491	SNARF	Liquid Filter TF	Reapproval of SEMI C82-0713: Test Method for Particle Removal Performance of Liquid Filter Rated 20 to 50 nm With Liquid-Borne Particle Counter
6491	Ballot	Liquid Filter TF	Reapproval of SEMI C82-0713: Test Method for Particle Removal Performance of Liquid Filter Rated 20 to 50 nm With Liquid-Borne Particle Counter

**Table 6 Authorized Activities**

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None.			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsba1.nsf/TFOFSNARF>

**Table 7 Authorized Ballots**

<i>#</i>	<i>When</i>	<i>TF</i>	<i>Details</i>
None.			

**Table 8 SNARF(s) Granted a One-Year Extension**

<i>#</i>	<i>TF</i>	<i>Title</i>	<i>Expiration Date</i>
None.			

**Table 9 SNARF(s) Abolished**

#	TF	Title
6479	Liquid Filter TF	Line Item Revision to SEMI C82-0713: Test Method for Particle Removal Performance of Liquid Filter Rated 20 to 50 nm With Liquid-Borne Particle Counter

**Table 10 Standard(s) to receive Inactive Status**

Standard Designation	Title
None.	

**Table 11 New Action Items**

Item #	Assigned to	Details
20190415_01	Mizue Iwamura (SEMI Japan)	To provide a list of participating companies for CMP PSD Working Group
20190415_02	Mizue Iwamura (SEMI Japan)	To provide a post-show report of SEMICON China 2019

**Table 12 Previous Meeting Action Items**

Item #	Assigned to	Details
20181212_01	Mizue Iwamura	To ask to the Standards Staff of North America that why “#6433: New Standard: Guide for Reporting Chemical Mechanical Planarization (CMP) Polishing Pad Hardness used in Semiconductor Manufacturing” is not test method. Closed.  To allow faster adoption by the industry. The Guide is more flexible for end user implementation, while the Test Method is very specific.



## 1 Welcome, Reminders, and Introductions

Hiroshi Tomita (Toshiba Memory Corporation) called the meeting to order at 15:05. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

**Attachment:** 01-02\_SEMI Standards Required Elements\_August2018\_E+J

## 2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

**Motion:** To approve the minutes of the previous meeting as written.

**By / 2<sup>nd</sup>:** Hiroyuki Araki (SCREEN Semiconductor Solutions) / Takuya Nagafuchi (Nihon Entegris)

**Discussion:** None.

**Vote:** 14 in 0 favor and 0 opposed. Motion passed.

**Attachment:** 02-01\_LC Minutes\_Draft\_20181212\_r2

## 3 Liaison Reports

### 3.1 *Gases and Liquid Chemical Europe TC Chapter*

None.

### 3.2 *Liquid Chemical North America TC Chapter*

Mizue Iwamura (SEMI Japan) reported for the Liquid Chemical North America TC Chapter as attached.

**Attachment:** 03-02\_NA Liquid Chemicals Liaison Report April 2019-v1

### 3.3 Semiconductor Components, Instruments, and Subsystems Technology Community (SCIS)

Mizue Iwamura (SEMI Japan) reported for the Semiconductor Components, Instruments, and Subsystems Technology Community (SCIS) as attached.

**Attachment:** 03-03\_SEMI SCIS Overview 2019Mar14\_Standards

### 3.4 Electronic Materials Group (EMG)

Mizue Iwamura (SEMI Japan) reported for the Electronic Materials Group (EMG) as attached.

**Attachment:** 03-04\_Overview of SEMI Electronic Materials Group-March019



### 3.5 SEMI Staff Report

Mizue Iwamura (SEMI) gave the SEMI Staff Report as attached.

**Attachment:** 03-05\_SEMI Staff Report 2019\_0409\_v1

## 4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 #6491: Reapproval of SEMI C82-0713: Test Method for Particle Removal Performance of Liquid Filter Rated 20 to 50 nm With Liquid-Borne Particle Counter

4.1.1 The ballot **passed** TC Chapter review as balloted and will be submitted to the ISC A&R for procedural review.

**Attachment:** 04-01\_6491\_Ballot report template with Technical Change Rev1.2(20190415)\_r2

## 5 Subcommittee and Task Force Reports

### 5.1 Diaphragm Valve Task Force

Kimihito Sasao (Advance Electric Company) reported that there is no issue currently working on.

### 5.2 Welding Fitting Task Force

Kimihito Sasao (Advance Electric Company) reported that there is no issue currently working on.

### 5.3 Liquid Filter Task Force

Takuya Nagafuchi (Nihon Entegris) announced that Takehito Mizuno (Pall) stepped down from Liquid Filter Task Force co-leader, and Tomoyuki Takakura (Pall) was proposed as his successor. He reported that the Liquid Filter Task Force is considering developing a new standard for a test method of metal removal.

Takuya Nagafuchi (Nihon Entegris) addressed to the committee on these topics.

**Motion:** To approve an appointment of Tomoyuki Takakura (Pall) as a new co-leader of Liquid Filter Task Force

**By / 2<sup>nd</sup>:** Takuya Nagafuchi (Nihon Entegris) / Hiroyuki Araki (SCREEN Semiconductor Solutions)

**Discussion:** None.

**Vote:** 13 in favor and 0 opposed. Motion passed.

**Motion:** To abolish #6479: SNARF for: Line Item Revision to SEMI C82-0713: Test Method for Particle Removal Performance of Liquid Filter Rated 20 to 50 nm With Liquid-Borne Particle Counter

**By / 2<sup>nd</sup>:** Takuya Nagafuchi (Nihon Entegris) / Tomoyuki Takakura (Pall)

**Discussion:** None.

**Vote:** 14 in favor and 0 opposed. Motion passed.

### 5.4 Liquid-borne Particle Counter Task Force

Kaoru Kondo (Rion) reported that there were no issue currently working on.



### 5.5 *Ultrapure Liquid Evaluation Study Group*

Takuya Nagafuchi (Nihon Entegris) addressed to the committee on this topic.

**Motion:** To approve a TFOF for Trace Metal Analysis for High Pure IPA Task Force  
**By / 2<sup>nd</sup>:** Takuya Nagafuchi (Nihon Entegris) / Hiroshi Sugawara (Organo)  
**Discussion:** None.  
**Vote:** 14 in favor and 0 opposed. Motion passed.

## 6 Old Business

### 6.1 *SNARF Project Period Check*

Mizue Iwamura (SEMI Japan) addressed that there is no SNARF that exceed the project period.

### 6.2 *5 Year Review Check*

Mizue Iwamura (SEMI Japan) addressed that there is no document to be addressed.

## 7 New Business

See 5.5 for the newly approved Task Force.

## 8 Next Meeting and Adjournment

The next meeting is scheduled for Dec 11-13, 2019 (TBD) at SEMICON Japan, Tokyo Big Sight, Tokyo, Japan.

See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: [16:45].



Respectfully submitted by:

Mizue Iwamura

Coordinator

SEMI Japan

Phone: +81-3-3222-5760

Email: [miwamura@semi.org](mailto:miwamura@semi.org)

Minutes tentatively approved by:

Hiroshi Tomita (Toshiba Memory), Co-chairs	May 22, 2019
Hiroyuki Araki (SCREEN Semiconductor Solutions), Co-chairs	May 22, 2019

**Table 13 Index of Available Attachments<sup>#1</sup>**

<i>Title</i>	<i>Title</i>
01-02_SEMI Standards Required Elements_August2018_E+J	03-05_SEMI Staff Report 2019_0409_v1
02-01_LC Minutes_Draft_20181212_r2	04-01_6491_Ballot report template with Technical Change Rev1.2(20190415)_r1
03-02_NA Liquid Chemicals Liaison Report April 2019-v1	
03-03_SEMI SCIS Overview 2019Mar14_Standards	
03-04_Overview of SEMI Electronic Materials Group-March019	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.